862.C2238

PATENT APPLICATION

IN THE UNITED STATES PATE	ENT A	AND TRADEMARK OFFICE
AUG 2 2 2003 In the Application of: In the Application of: Application No.: 09/865,454)	Examiner: Unassigned Group Art Unit: 2881
Filed: May 29, 2001)	
For: EXPOSURE APPARATUS, DEVICE MANUFACTURING METHOD, SEMICONDUCTOR MANUFACTURING PLANT AND METHOD OF MAINTAINING EXPOSURE APPARATUS)	August 27, 2001

Commissioner for Patents Washington, D.C. 2023 I

CLAIM TO PRIORITY

Sir:

Applicant hereby claims priority under the International Convention and all rights to which he is entitled under 35 U.S.C. § 119 based upon the following Japanese Priority Application:

JAPAN

2000-163845

May 31, 2000

A certified copy of the priority document is enclosed.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010 All correspondence should continue to be directed to our address given below.

Respectfully submitted,

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JAPAN **PATENT OFFICE** 09/865,454 Shigeyuli Uzawa May 29,2001

別紙添付の書類に記載されている事項は下記の出願書類に記載されて いる事項と同一であることを証明する。

This is to certify that the annexed is a true copy of the following application as filed with this Office

AU6 2 2 2003 公出 願 年 月 日 Date of Application:

2000年 5月31日

出 Application Number:

特願2000-163845

出 願 人 Applicant(s):

キヤノン株式会社

2001年 6月12日

特許庁長官 Commissioner, Japan Patent Office

